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# Implementation of AOI in a High-Volume Manufacturing Environment

*Presented By*

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# Overview

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- Previous process at this Fab
- What was implemented
- Improvements in process resulting from NSX implementation
- Tremendous benefits resulting from NSX implementation
- Payback \$\$\$
- The improvements possible in your Fab

# Customer Fab

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- 100mm Fab shipping sawn wafers offshore for assembly
- Utilized manual inspection with paper trails for T&A inspection and tracking of defects
- Wafer maps were not used in the process
  - *prober map did not go to assembly, etc...*
- Defect categories, location and die count data recorded on paper by operator
- Inking wafers for pick and place

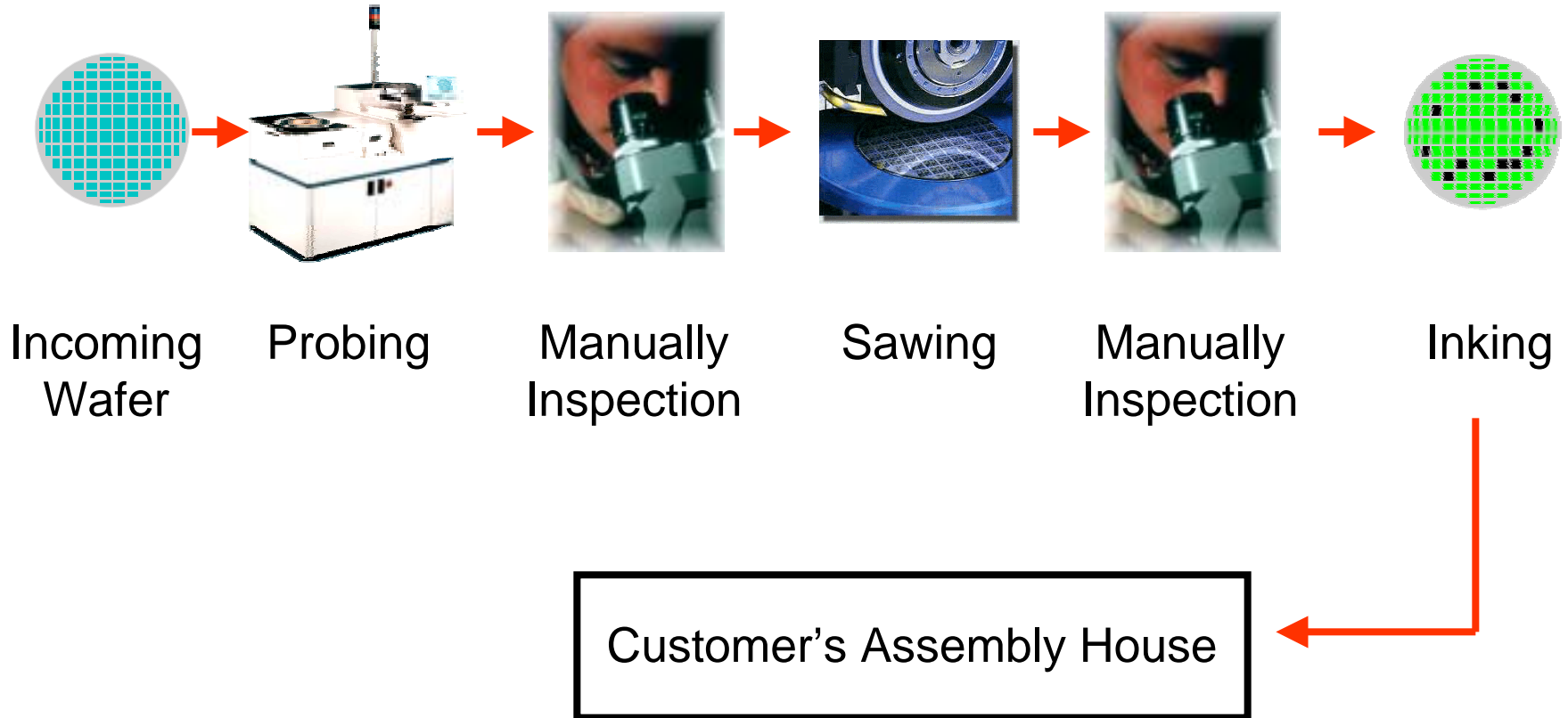
# What was wrong?

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- Defects not being found during inspection
- Die count variances between customer and foundry assembly site
- Inaccurate recording of defect location and type
  - *only as accurate as the operator made it*
- No quick feedback to engineering
- Inking
- Major production ramp
  - *could not train or hire enough operators to meet ramp*

# Customer's Previous Process

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# Solving the problems

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- NSX-90 automatic visual inspection
- Electronic wafer maps
- Wafer map server (*provided by customer*)
- Offline review
- Automatic defect classification

# NSX-90 Capabilities Implemented

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- Automated Optical Inspection
- Wafer Map Import/Update and Export
- Auto Retrain- *automatically modifies inspection recipe as your process changes*
- Defect Classification Coding (*currently manual*)
- Film Frame Handling
- Automated Defect Classification
  - *Currently being phased in over next quarter*

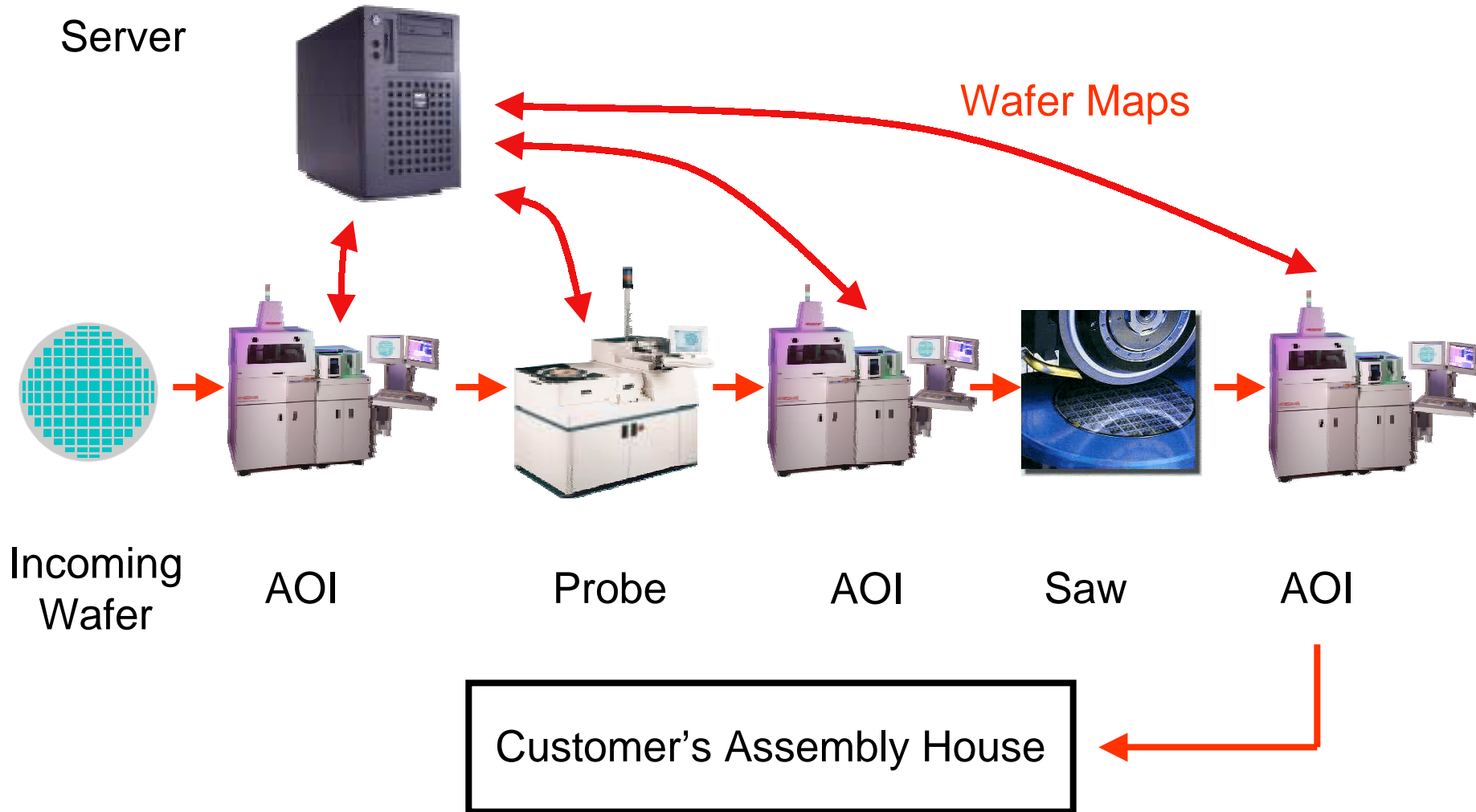
# NSX-90 Specifications

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- Defect Sensitivity down to 0.5 microns
  - *Typically 10 micron in this application*
- Repeatability greater than 95%
- Uptime greater than 97%



# Enhanced Process



# Results

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- Elimination of inking
  - *Wafers sent to offshore assembly house with electronic wafer maps*
- Accurate recording of defects
  - *Location*
  - *Classification*
- Wafer maps implemented
- Elimination of manual inspection
- “Real time” review of defects

# “Tangible” Benefits

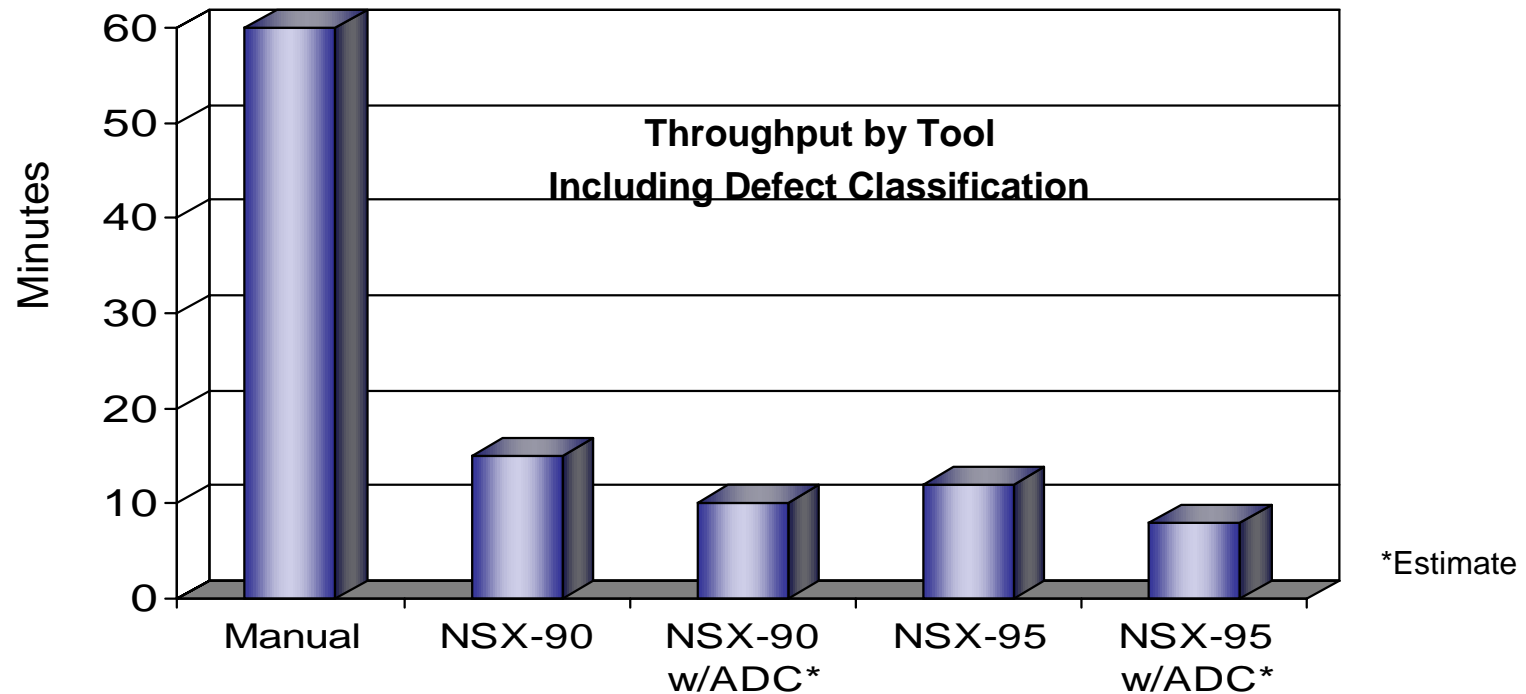
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- Inking process step removed
  - *Saved time, resources and floor space*
  - *Eliminated chance of inking wrong die*
- Pick and place defects eliminated
  - *Locating ink dots not required*
  - *Wafer maps sent to “end customer”*
- Count variance issues eliminated
  - *Customer count discrepancies due to operator miscount*  
*“We shipped 10k and they received 9.5k?”*

# Throughput Improvement

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*“The NSX-90 alone cut inspection cycle time by a factor of 4 when compared to manual inspection”*



# Yield Improvement

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Added 1.5% to yield numbers  
=  
60,000 additional good die per week  
=  
**Payback in 8 weeks**

# Intangible Benefits

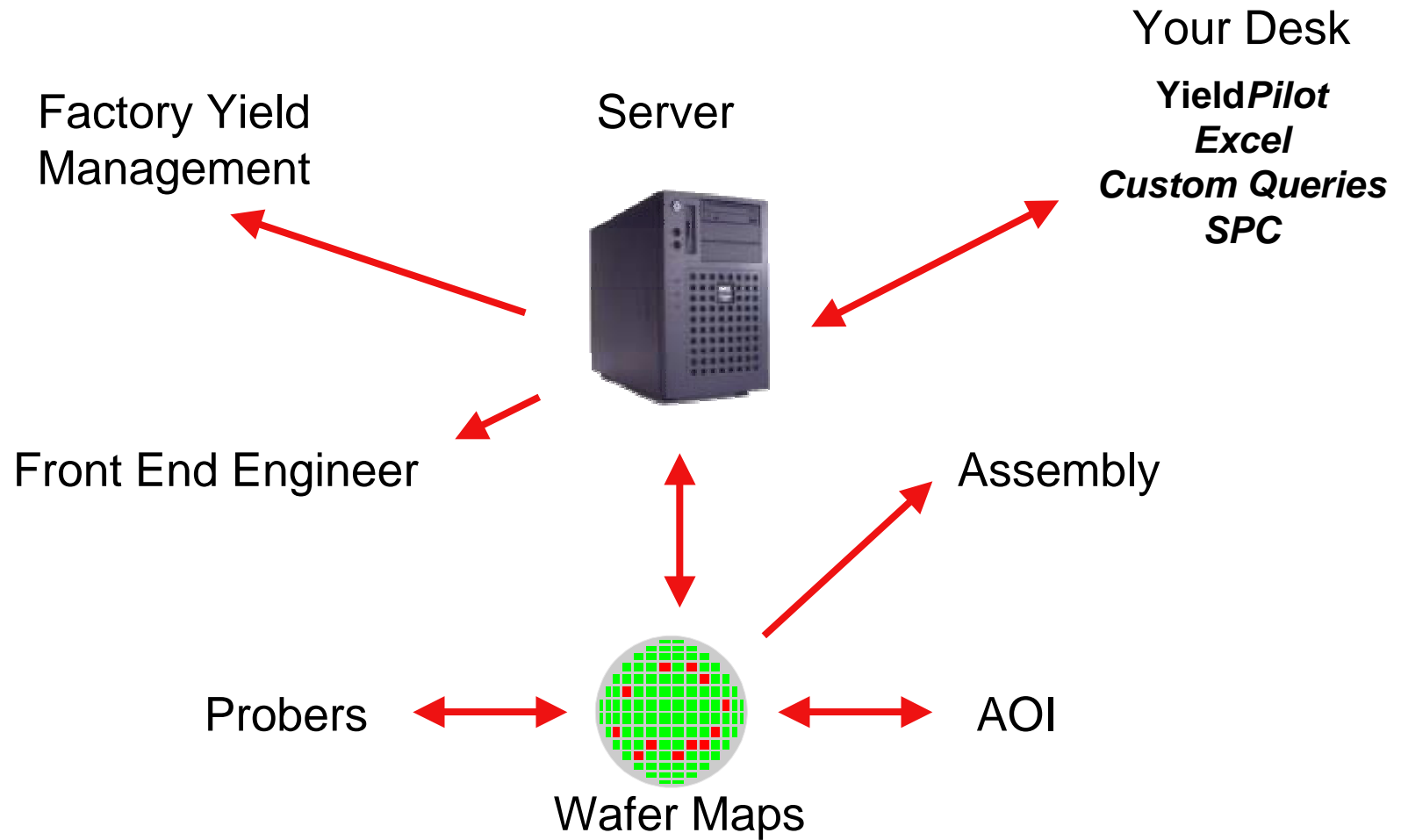
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- Higher end-customer satisfaction due to higher quality of incoming products - *making their job easier!*
- Reduced human fatigue as operators are not looking through microscopes 8 hours a day
- Ergonomic improvements
- Operators utilized for other tasks- speeds ramp up
- Confidence in inspection –  
“*The NSX does not miss defects - operators do*”

Quote from manager at customer site

# Ultimate Data Distribution - *Where*

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# What Data Can We Provide?

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- Bump inspection
  - Diameter, height, area, presence, shape, coplanarity,...
- Probe mark
  - Presence, area, boundary intrusion  
and/or
  - Location on pad (4 dims), area, number of marks
- Active Area
  - Chips, cracks, particles, FM, ...
  - Saw damage



# How Much Data Can You Get?

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## **Tons of Data from Probe or Bump Metrology**

2400 die, 8 pads, 100% Inspection, 1000 wafer/day

<b>Wafer</b>	230,400	12.8 Mb
<b>Lot</b>	5,760,000	320 Mb
<b>Day</b>	230,400,000	12 Gb

## **Thinking 300mm?**

Count on approximately 41 Mb of data  
per wafer for full metrology!!!

# Implementation of the NSX

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- Increased Fab productivity and profits
  - Improvements in your process through use of accurate and complete data
  - Elimination of process steps that are dirty or prone to create defects - i.e.- *Inking*
  - Yield improvements- *quality of work as well as process improvements*
  - Throughput, throughput, throughput
- Quality of work improvements
  - Higher quality inspection and accurate data
  - Improved job satisfaction - *Operators do not sit in front of a microscope for 8 hours = less turnover*

# August Technology

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- Founded 1993
- Bloomington, MN
- Cassette and FOUP inspection
- Automated visual inspection
- Bump, probe and sawn wafer inspection
- Over 85 NSX systems installed worldwide
- Wafer, film frame & Auer boat handling

# August Technology's Post-Fab

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- Whole wafers
  - Active die area, bond pads, bump
- Sawn wafers
  - Chips, FM, cracks, scratches...
- Die in waffle pack or Gel-pak
- Yield*Pilot*<sup>TM</sup> – defect data and process analysis
  - Data server
  - Browser integration
- **300mm inspection ready today!**

# Contact Information

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